



2812

MacPherson Kwok Chen & Heid LLP

2001 Gateway Place, Suite 195E

San Jose, CA 95110

Tel. (408) 392-9250

Fax (408) 392-9262

Email: mailbox@macpherson-kwok.com

2402 Michelson Drive, Suite 210

Irvine, CA 92612

Tel. (949) 752-7040

Fax (949) 752-7049

RECEIVED
JAN-2 2003
TECHNOLOGY CENTER 2800

December 17, 2002

BOX AMENDMENT
Commissioner For Patents
Washington, D.C. 20231

Re: Applicant(s): Woo Sik Yoo
Assignee: WaferMasters, Inc.
Title: Method for H2 Recycling In Semiconductor Processing System
Serial No.: 09/828,518
Examiner: Olivia T. Luk
Docket No.: M-8608US
Filed: April 6, 2001
Group Art Unit: 2812

Dear Sir:

Transmitted herewith are the following documents in the above-identified application:

- (1) Return Receipt Postcard;
- (2) This Transmittal Letter (in duplicate);
- (3) Response to Office Action (7 pages).

- ☒ No additional fee is required.
☐ The fee has been calculated as shown below:

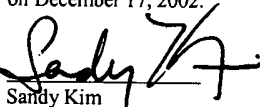
CLAIMS AS AMENDED

	Claims Remaining <u>After Amendment</u>		Highest No. Previously <u>Paid For</u>		Present <u>Extra</u>		Rate		Additional <u>Fee</u>
Total Claims	20	Minus	20	=	0	x	\$18.00	\$	0
Independent Claims	3	Minus	3	=	0	x	\$84.00	\$	0
<input type="checkbox"/> Fee for Request for Extension of Time								\$	
<u>Total additional fee for this Amendment:</u>								\$	

- ☒ Conditional Petition for Extension of Time: If an extension of time is required for timely filing of the enclosed document(s) after all papers filed with this transmittal have been considered, an extension of time is hereby requested.
- ☐ Please charge our Deposit Account No. 50-2257 in the amount of \$
- ☒ Also, charge any additional fees required and credit any overpayment to our Deposit Account No. 50-2257

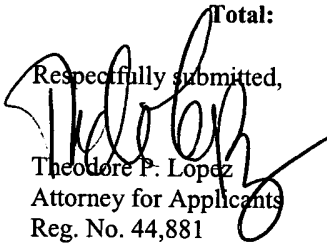
Total: \$ 0

I hereby certify that this correspondence is being deposited with the U.S. Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, Washington, D.C. 20231, on December 17, 2002.


Sandy Kim

December 17, 2002

Respectfully submitted,


Theodore P. Lopez
Attorney for Applicants
Reg. No. 44,881



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

RECEIVED

JAN -2 2003

TECHNOLOGY CENTER 2800

Applicants: Yoo, Woo Sik

Assignee: WaferMasters, Inc.

Title: Method for H₂ Recycling in a Semiconductor Processing System

Serial No.: 09/828,518

Filing Date: April 6, 2001

Examiner: Luk, Olivia T.

Group Art Unit: 2812

Docket No.: M-8608 US

Irvine, California
December 17, 2002

BOX AMENDMENT
COMMISSIONER FOR PATENTS
Washington, D. C. 20231

RESPONSE TO NON-FINAL OFFICE ACTION

#13/A
1/22/03

Dear Sir:

In response to the Office Action dated September 18, 2002, Applicants submit the following amendments and remarks.

IN THE CLAIMS

The following is a clean version of the entire set of pending claims. In accordance with 37 C.F.R. §1.121(c)(1)(ii), Attachment A provides a marked-up version of the claims containing the newly introduced changes.

Please add new Claims 16-28. Please amend Claims 1 and 3-5 as follows.

01/23/2003 JSIMMONS 00000004 502257 09828518

01 FC:2201
02 FC:2202

04.00 CH
72.00 CH

LAW OFFICES OF
MACPHERSON KWOK CHEN
& HEID LLP

2402 Michelson Drive
Suite 210
Irvine, CA 92612
(949) 752-7040
FAX (949) 752-7049

1. (Amended) A process for recycling a vapor-phase chemical comprising:
introducing vapor-phase chemicals including a first gas into a reactor with sufficient
supplied energy to cause a first reaction in said reactor;
exhausting gases from said reactor resulting from said reaction;
separating a second gas from said exhausted gases;